

Master's Thesis Supervision

- Plasma etching simulation of SiO₂ and Si in fluorocarbon Plasmas, G. Kokkoris, Masters in Microelectronics, 1999
- Plasma Etching of Polymers in High Density Oxygen Plasmas, G. Kordogiannis, Masters in Microelectronics, 2000
- Computational Analysis of Contact Hole Etching, A. Koulidis, Masters in Computational Analysis, 2001
- Roughness formation during Si plasma etching, K. Boukouras, Masters in Microelectronics, 2003
- AFM measurement of surface roughness after plasma etching, O. Brani, Masters in Microelectronics, 2004
- Selective deposition of fluorocarbon films and application in protein arrays, Matrozos Evrymahos, Masters in Polymer Science and Engineering 2005
- Fabrication and simulation of microstructures by plasma processing, Papassimakis Panagiotis, Masters in microsystems 2005
- Modification of PDMS surfaces in O₂-based plasmas, Tsougeni Katerina, Masters in Polymer Science and Engineering 2005
- Global models for plasma chemistry simulation, P. Geka, Masters in Mathematical simulation, 2006
- Simulation of plasma etching of composite materials, E. Zakka, Masters in Microelectronics, 2006
- Plasma etching of rough surfaces using level set methods, P. Xidi, Masters in Microelectronics, 2006
- Monte-Carlo roughening during thin film plasma etching, P. Angelikopoulos, Masters in Mathematical Simulation 2006
- Silylation and Dry Development of SU8 photoresist, D. Kontziambasis, Masters in Microelectronics, 2007
- Global models for plasma chemistry in SF₆ and C₄F₈ discharges, A. Panagiotopoulos, Masters in Microsystems, 2008
- Plasma etching of polymers for microfluidics fabrication and sealing, K. Kontakis Masters in Microelectronics, 2008
- Dual scale superhydrophilic, superhydrophobic, and oleophobic surfaces fabricated by colloidal lithography and plasma etching, K. Ellinas, Masters in Microelectronics, 2009
- Fabrication of polymeric microfluidic channels with nanostructured walls: Characterization of the nanostructure and measurements of the pressure drop on water flow, D. Papageorgiou, Masters in Microelectronics, 2009
- Monte Carlo simulation of ion enhanced etching of polymers using a random walk representation of the polymer chains, A. Anastasopoulos, Masters in Microelectronics, 2009

- Cryogenic Etching Process for Silicon Micro and Nanostructures
Athanasios Smyrnakis, School of Applied Mathematical and Physical Sciences(NTUA), MSc
- Fabrication of a microfluidic device for DNA amplification, Efstathia Mavraki, School of Applied Mathematical and Physical Sciences(NTUA), MSc
- Peak-centered correlation function analysis of the order degree of surface morphologies
Dimitrios Zervas, Electrical Engineer, MSc
- Entropy analysis of natural language, Maria Kalimeri, Physicist, MSc
- Nanopillars and vertical silicon nanowires fabrication using silicon plasma etching processes in room temperature Angelos Zeniou, Electronic Engineering, Masters in Microelectronics
- Mathematical modeling of a continuous flow microfluidic device for DNA amplification by Polymerase chain reaction (PCR), Elias Kouris, Masters in Microelectronics
- Analysis of Rough Surfaces with Network Theory, Nikoletta Karasmani, School of Applied Mathematical and Physical Sciences(NTUA), MSc
- Water and Low Surface Tension liquid flow fields in superhydrophilic and superhydrophobic microchannels studied by micro PIV, Andreas Passos, NTUA
- Simulation of surface charging during plasma etching of dielectric microstructures, George Memos, Masters in Microelectronics
- Simulation of the gas phase of plasma reactors with detailed models, Sotiris Mouchtouris, Masters in Microelectronics
- Fabrication of plasma nanotextured superhydrophilic and superhydrophobic microchannels and water flow field measurement via micro PIV, Theodore Christophoridis, NTUA